PLASMA PROCESSING APPARATUS

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ABSTRACT OF THE DISCLOSURE

A plasma processing apparatus for supplying radiofrequency power into a process chamber so as to generate
plasma, to thereby treat an object to be processed with
the plasma. In the plasma processing apparatus, the
process chamber has a top plate which is disposed
opposite to the object to be processed, through the
medium of a region for generating the plasma, and a
radio-frequency antenna is disposed in the inside and
outside of the process chamber so that the radiofrequency antenna is wound around the top plate.